

PAPER



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Localized optical-quality doping of graphene on silicon waveguides through a TFSA-containing polymer matrix†

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The use of graphene in optical and photonic applications has gained much attention in recent years. To maximize the exploitation of graphene's extraordinary optical properties, precise control over its Fermi level (e.g. by means of chemical doping) will be of vital importance. In this work, we show the usage of a versatile p-doping strategy based on the incorporation of bis(trifluoromethanesulfonyl)amide (TFSA), functioning as an active p-dopant molecule, into a poly(2,2,3,3,4,4,5,5-octafluoropentyl methacrylate) (POFPMA) polymer matrix. The TFSA/POFPMA dopant can be utilized both onto large size graphene regions via spin coating and on small predefined spatial zones of micrometer dimension by localized inkjet printing. Whereas pure TFSA suffers from a clustered layer deposition combined with environmental instability, the application of the POFPMA polymer matrix yields doping layers revealing superior properties counteracting the existing shortcomings of pure TFSA. A first key finding relates to the optical quality of the dopant layer. We obtain a layer with an extremely low surface roughness (0.4–0.8 nm/25 μm²) while exhibiting very high transparency (absorbance <0.05%) over the 500–1900 nm wavelength range, with strongly enhanced doping stability as a function of time up to several weeks (for inkjet-printed deposition) and months (for spin coated deposition). Finally, the doping efficiency is very high, reaching a carrier density around $+4 \times 10^{13} \text{ cm}^{-2}$ whereas the optical transmission of a graphene-covered Si waveguide revealed a strong improvement (4.22 dB transmission increase per 100 μm graphene length at the wavelength of 1550 nm) after deposition of the dopant via inkjet printing.

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1. Introduction

Ever since graphene was isolated in 2004,¹ it has been the subject of breakthrough research due to its outstanding and unique physical properties.² The two-dimensional material consisting of sp²-hybridized carbon atoms organized into a honeycomb lattice,

exhibits extraordinary electrical characteristics (*i.e.* high electron mobility³ at room temperature ($\mu = 2 \times 10^5 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$) and exceptional mechanical robustness (intrinsic strength and elasticity of $\sigma_{\text{int}} = 130 \text{ GPa}$ and $E = 1 \text{ TPa}$, respectively⁴).

In addition, graphene is also characterized by specific optical properties. As a result, graphene can be integrated into a variety of photonic applications.⁵ Indeed, pristine graphene exhibits a strong linear optical absorbance of 2.3% per layer, independent of the wavelength⁶ and mainly caused by interband transitions.⁷ Furthermore, it is known that graphene features a very strong nonlinear response.⁸ Hendry *et al.*⁹ determined the Kerr susceptibility of graphene ($\chi^{(3)}$) to be 10^{-7} esu (electrostatic units) using four-wave mixing (FWM). Recently, the Kerr nonlinearity of graphene on a silicon waveguide was measured by chirped-pulse-pumped self-phase modulation (SPM),¹⁰ which yielded the same magnitude as measured by Hendry *et al.* and additionally, revealed a negative nonlinearity sign. Earlier this year, our group showed that rather than the nonlinear susceptibility, a complex saturable refraction process is central

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to graphene's SPM behavior.¹¹ Covering an optical waveguide with graphene results in an interaction between the evanescent tails of the guided light through the waveguide and the deposited graphene monolayer. As a result, the performance of a photonic chip will change significantly both in terms of optical losses (due to the strong linear absorbance of graphene^{12,13}) as well as nonlinear behavior (due to the strong nonlinearity of graphene^{10,11}). As a result, the improved nonlinear optical functionality of graphene deposited onto a waveguide-based photonic device can play an important role in the development of on-chip nonlinear-optical light sources.^{13,14} However, the output power of the chip decreases drastically with the increasing length of the graphene-covered waveguide due to graphene's strong absorbance.

Another remarkable property of graphene is the ability to tailor its electronic and optical characteristics by shifting graphene's Fermi level. The position of the Fermi level is dependent on the type and concentration charge carriers in graphene, which can be altered by graphene doping. The applied dopant strategy is able to either extract electrons from graphene (p-type doping, resulting in a shift of the Fermi level below the Dirac point) or donate electrons to graphene (n-type doping, resulting in a shift of the Fermi level above the Dirac point). However, for most optical applications of graphene, only the magnitude of the graphene Fermi level is important rather than its sign.¹⁵ Indeed, for both n- and p-type doping, the linear optical absorbance will be lower as a consequence of suppressed interband transitions, which is a necessity for graphene's optical usability.

One way to shift the Fermi level is *via* electrical gating; by applying a gate voltage onto a dielectric or electrolyte in contact with graphene, the position of the Fermi level can be precisely tuned from conduction to valence band.¹⁶ Another common approach to control the carrier type and density in graphene is based on chemical doping,¹⁷ a technique which can be subdivided in substitutional doping (several carbon atoms in the graphene layer are replaced by an atom with a different number of valence electrons) and surface transfer doping (dopant molecules are adsorbed onto the graphene surface to induce an electron exchange between graphene and the adsorbed layer). A last, but less frequently applied doping approach, classified within chemical doping, is based on covalent functionalization of graphene. This can be achieved for example by treatment with chlorine plasma¹⁸ or electron beam lithography.¹⁹

Whereas electrical gating of graphene is flexible and tunable upon changing the gate voltage, chemical doping offers a permanent doping level depending on the dopant strength and applied dopant concentration.²⁰ Although the former results in very promising doping efficiencies (n ranging from $-3 \times 10^{13} \text{ cm}^{-2}$ to $+4 \times 10^{13} \text{ cm}^{-2}$, with n being charge carrier concentration²¹), it requires advanced nanofabrication techniques for positioning electrical contacts and the usage of a voltage source,²² which is not always desirable, nor possible. Additionally, a noteworthy hysteresis effect is observed upon gating graphene with electrolytes.²³ Consequently, chemical doping will be our main focus for controlling graphene's Fermi level. Because substitutional doping and covalent functionalization lead to invasive alterations of graphene's crystalline structure with subsequently

deteriorated carrier mobility and conductivity,²⁴ we select the surface transfer approach as the most promising one for graphene doping towards optical applications.

Chemical doping of graphene for optical applications needs to comply with essential requirements in order to maintain graphene's unprecedented qualities in the optical application domain. First, the method needs to be efficient and stable over time. Secondly, the applied dopant layer needs to be of high optical quality, *i.e.* it should be highly transparent (light absorption $< 0.05\%$, for every applied layer regardless its thickness, in the visible, near and mid-infrared, because this includes the region of interest for many on-chip optical applications) with a low surface roughness (root mean square (RMS) roughness $< 5 \text{ nm}$ or an optical quality of $\lambda/200$ at $\lambda = 1000 \text{ nm}$ over a surface of $25 \mu\text{m}^2$) to avoid additional optical light scattering when light passes through the doped graphene. Finally, the doping strategy should be preferably straightforward to apply.

Graphene, grown on copper and transferred on the desired substrates, already features unintentional p-type doping as a consequence of air exposure and PMMA residues associated with the graphene transfer.^{25,26} Consequently, the present work focusses on a strategy to further increase the p-doping efficiency. Therefore, when looking at surface transfer doping, strong electron acceptor molecules will have to be applied to extract electrons from graphene, thereby further lowering its chemical potential. This can be achieved by using different dopant molecules, including inorganic acids^{27,28} (H_2SO_4 , HNO_3 , HCl , HAuCl_3), transition metal oxides (MoO_3 ^{29,30} and VO_x ³¹), strong organic π -electron acceptors (*e.g.* F4-TCNQ³²), organic acids (TFSA^{33–35} and TFMS³⁶) and metal chlorides^{37–39} (AuCl_3 , RhCl_3 and FeCl_3). However, to the best of our knowledge, the chemical doping methods reported so far, do not fulfill the requirements in terms of optical quality due to a rough surface^{38,40,41} and corresponding optical loss of at least 1% for light passing perpendicularly through the graphene sheet^{35,41,42}. In addition, some of the applied dopant layers suffer from poor stability due to time-dependent desorption of adsorbed dopants.^{43,44} Recently, another approach towards surface transfer doping was developed, namely photoinduced charge transfer.^{22,45–47} The latter technique however requires back-gated sample design⁴⁶ and a controlled atmosphere by continuous illumination,²² which cannot, to the best of our knowledge, be considered as easily applicable in future optical applications. We recently reported on a new p-type doping strategy with optical quality, based on a spin coated F4-TCNQ/MEK layer.⁴⁸ In that work, a controllable change in doping efficiency, expressed in change of charge carrier concentration Δn , ranging between $+5.7 \times 10^{12} \text{ cm}^{-2}$ and $+1.1 \times 10^{13} \text{ cm}^{-2}$ was obtained, which was 50% higher in comparison with that obtained by F4-TCNQ applied by vapour deposition³² and simultaneously fulfilled the above mentioned optical quality requirements. Nevertheless, a further improvement of the doping efficiency is desirable.

Another critical point related to the use of graphene and its doping, is the deposition and the patterning. Chemical vapor deposition (CVD) grown monolayer graphene can be transferred on different types of substrates:⁴⁹ rigid substrates (*e.g.* glass,

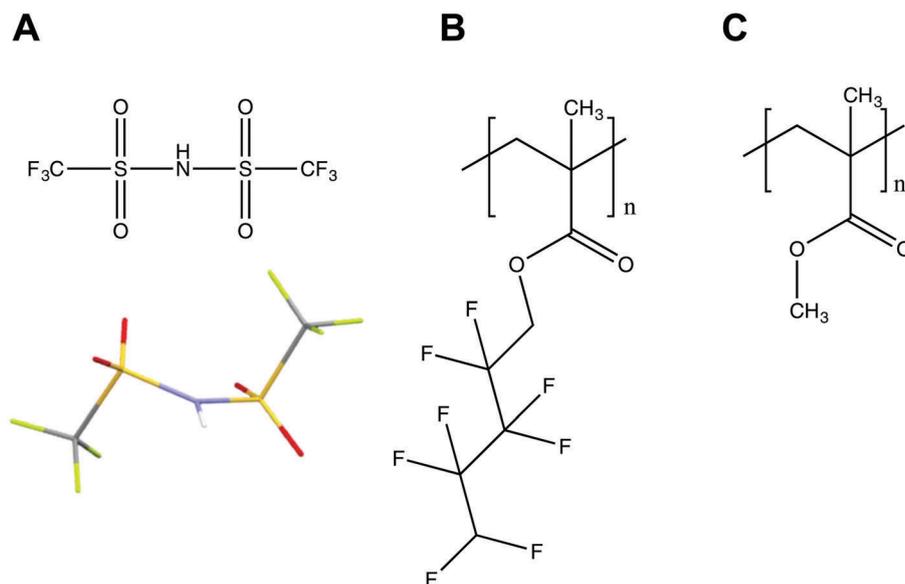


Fig. 1 Chemical structures of (A) TFSA, (B) POFPMA and (C) PMMA. Additionally, the crystal structure of TFSA is presented with the carbon atoms represented by grey, fluorine atoms by green, hydrogen atom by white, nitrogen atom by blue, oxygen atoms by red and sulfur atoms by yellow colors.

quartz, silicon (Si), silicon dioxide (SiO_2)) and flexible substrates (*e.g.* PET).⁵⁰ Depending on the desired application, we aim for either continuous graphene covering a large substrate surface ($0.5 \text{ cm}^2\text{--}1 \text{ m}^2$ range)⁵¹ or smaller graphene domains covering specific structures (micro- to nanometer scale on *e.g.* optical waveguides or field effect transistors (FET)).^{10–12,52} As a consequence, the doping deposition technique needs to be adjusted, depending on its final application: chemical doping on large graphene areas is frequently applied by spin coating (wet-chemical doping approach) or thermal evaporation,⁵³ whereas localized dopant patterning still remains a niche.⁵⁴ The existing localized doping methods include different kinds of lithography and patterning techniques^{55–57} for specific dopants (*e.g.* gold nanoparticles) which are not optimized for establishing optical-quality doping as we target here.

In this paper, we describe a new optical doping strategy based on surface transfer p-doping of graphene for optical applications and with the possibility for localized doping. The selected strategy should meet a predefined set of requirements. First, we aim for an optical-quality doping strategy revealing higher doping efficiencies than previously obtained with the F4-TCNQ/MEK dopant layer ($\Delta n > +2 \times 10^{13} \text{ cm}^{-2}$, with the aim to compete with the electrolyte-based graphene gating efficiencies). Secondly, the strategy should enable region-controlled micrometer-sized deposition on large scale substrates. We propose inkjet printing as a novel localized doping method to obtain lower light absorption in graphene-covered on-chip optical waveguides. The optical waveguides that we consider are Si waveguides, with Si being a primary material platform for on-chip data transmission at the telecom wavelength of 1550 nm.⁵⁸ Moreover, Si waveguides can be manufactured by means of Complementary Metal Oxide Semiconductor (CMOS) technology, enabling high-volume fabrication at low cost.⁵⁸

Silicon photonics, could potentially also be combined with silicon electronics creating hybrid integrated optoelectronic systems.⁵⁹

A first step towards such a doping strategy is the selection of a suitable p-type dopant, namely bis(trifluoromethanesulfonyl)amide (TFSA, $[\text{CF}_3\text{SO}_2]_2\text{NH}$) (Fig. 1A). We select TFSA because, to the best of our knowledge, it is the strongest p-type dopant currently existing, due its extremely strong acidity ($\text{p}K_{\text{a}} = -11.9$) yielding intrinsic strong electron accepting properties.^{33,42,60–62} However, TFSA dissolved in *e.g.* nitromethane and subsequently spin coated onto graphene suffers from micrometer-sized clusters being formed.³⁸ Furthermore, optical transmission losses of at least 1% were described using perpendicularly incident light (for λ in the visible or infrared) on TFSA-deposited graphene.^{35,53,63} Given its strong acidity, a final TFSA shortcoming is the water sensitivity although contradictory findings have been reported in literature on this matter.^{42,61}

With the aim to overcome the above-mentioned TFSA-related issues, we propose poly(2,2,3,3,4,4,5,5-octafluoropentyl methacrylate) (POFPMA, Fig. 1B) as polymer matrix for incorporating TFSA. The choice for POFPMA rather than PMMA (often used in graphene processing) originates from the inferior properties of both high ($M_{\text{w}} = 350\,000 \text{ g mol}^{-1}$) and low ($M_{\text{w}} = 6000 \text{ g mol}^{-1}$) molecular weight poly(methyl methacrylate) (PMMA, Fig. 1C) in terms of the solubility and the mechanical stability, respectively.

The present paper covers two interrelated parts. First, the chemical characterization of the TFSA/POFPMA dopant layer and the quantification of the doping efficiency for larger areas obtained through spin coating are described. The second part focusses on the spatially controlled deposition of the TFSA/POFPMA dopant through inkjet printing with a final application on graphene-covered waveguides.

2. Results and discussion

2.1 TFSA/POFPMA doping on graphene on top of flat Si samples by spin coating

2.1.1 Characterization of the spin coated TFSA/POFPMA layer. Acids are often used as p-doping molecules on graphene, due to their oxidizing effect; the acidic proton(s) can cause a charge transfer by extracting electrons from graphene.^{27,51,64,65} We studied the doping effect of various acids in function of their acidity level (expressed in pK_a units) and used transferred graphene onto Si samples as substrate with a polished top side exhibiting a very high surface quality. We concluded that the p-doping effect increases with a higher acidity strength. The results are included in the ESI,† Fig. S1. Since TFSA (Fig. 1A) is categorized as a super acid ($pK_a = -11.9$), it is a commonly used strong p-dopant which can moreover be easily applied by spin coating in *e.g.* nitromethane.⁴² However, for the solvents used to date for TFSA on graphene, the spin coated deposition features particle formation⁴¹ (Fig. 2A), which is detrimental for optical applications.^{66,67} In addition, the spin coated TFSA deposition on graphene suffers from temporal instability when exposed to the atmosphere, due to its high sensitivity to humidity.⁴²

To counteract these shortcomings, we incorporated TFSA as active dopant molecule into a POFPMA polymer matrix (Fig. 1B) as PMMA could not fulfill the role as candidate matrix material (see introduction and further detailed below). Knowing that PMMA (Fig. 1C) is very often used as supporting layer for transferring graphene, we selected POFPMA as it is also a polymethacrylate in which the fluorine atoms in the side chains are likely to benefit the transparency due to the lower energy absorption bands of

fluorine compared to hydrogen.⁶⁸ The matrix polymer POFPMA was used directly after synthesis without any further purification due to the absence of a solvent during the bulk polymerization. The molecular weight (M_w) of the synthesized POFPMA was determined at 3200 g mol^{-1} (with a polydispersity (D) of 1.99), the degradation temperature ($T_{d,95}$) at $243 \text{ }^\circ\text{C}$ and the glass transition temperature (T_g) at $17 \text{ }^\circ\text{C}$. We anticipated that the low T_g -value of the bulk POFPMA will not impose any problems given the high surface energy of graphene, leading to an increased T_g of the obtained thin polymer films.^{69–71}

We noted that while using PMMA as a 10 w/v% in ethylacetate with a high molecular weight (M_w of $350\,000 \text{ g mol}^{-1}$) and a T_g of $105 \text{ }^\circ\text{C}$, typically used for transferring graphene, to incorporate the TFSA dopant, led to more clustered surfaces (RMS roughness of $2.4 \text{ nm}/25 \mu\text{m}^2$). PMMA with a lower molecular weight (M_w of 6000 g mol^{-1}), a T_g of $75 \text{ }^\circ\text{C}$ and applied from a 20 w/v% in acetone though, resulted in a cracked layer after drying. We therefore concluded that POFPMA revealing a M_w of 3200 g mol^{-1} and a T_g of $17 \text{ }^\circ\text{C}$ and applied from a 20 w/v% solution in acetone, offered a good compromise with its lower molecular weight sustaining good solubility thus guaranteeing a uniform film formation and its lower T_g enabling smoother surfaces to be obtained.

Optical microscopy analyses of the spin coated layers, consisting of TFSA (0–40 mM) and POFPMA (20 w/v%) in acetone onto graphene, revealed a uniform and cluster-free surface (Fig. 2B). Additionally, SEM images of the TFSA/POFPMA dopant layer are presented in the ESI,† (Fig. S2).

The roughness of the spin coated TFSA/POFPMA layer was determined by atomic force microscopy (AFM). While a bare

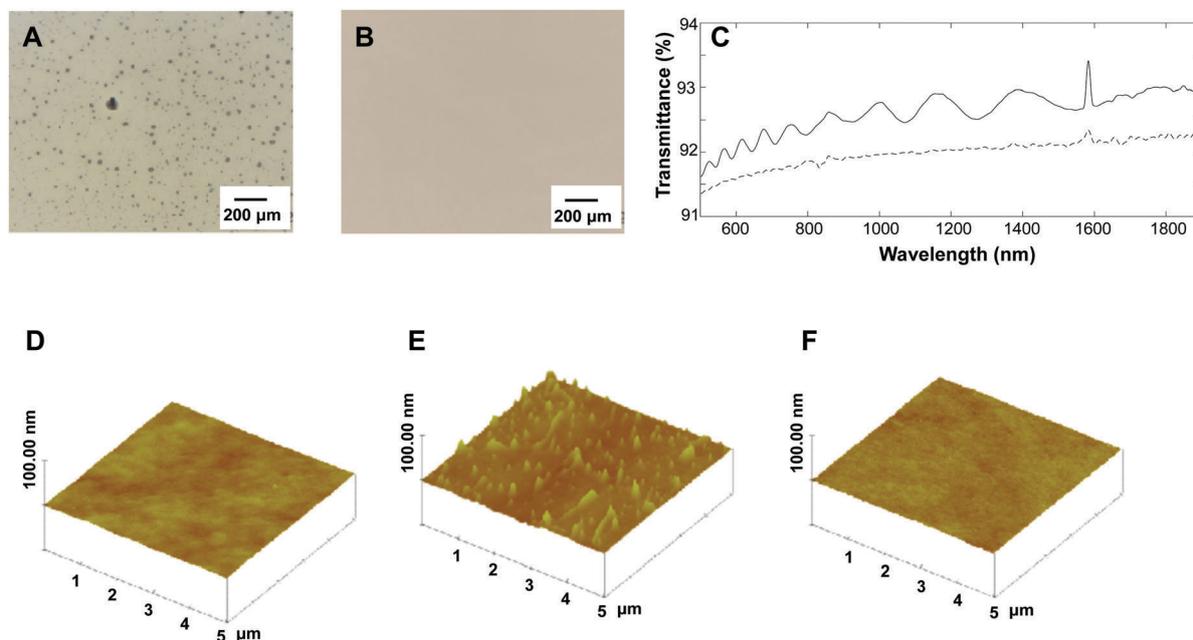


Fig. 2 Analysis of the optical quality of the TFSA/POFPMA dopant layer: optical microscopy image of (A) TFSA (20 mM) dissolved in nitromethane and (B) TFSA/POFPMA (20 mM TFSA and 20 w/v% POFPMA) dissolved in acetone, spin coated onto graphene. (C) Optical transmittance of a glass substrate (dashed line) and TFSA/POFPMA spin coated on glass (full line). AFM 3D surface plots of (D) a polished Si sample with a (E) transferred monolayer graphene on top and (F) additionally covered with a spin coated TFSA/POFPMA layer.

Table 1 XPS results of a bare graphene-covered Si substrate and a spin coated TFSA/POFPMA layer on a graphene-covered Si substrate (concentration TFSA = 20 mM). The table summarizes the average values and the corresponding standard deviations derived from measurements at three randomly selected positions on the surface

Element	Monolayer graphene transferred on Si		TFSA/POFPMA spin coated on graphene	
	Average (%)	Std dev. (%)	Average (%)	Std dev. (%)
O	24.99	0.8	9.9	0.2
C	47.63	1.2	44.28	0.6
F	—	—	45.83	0.7
Si	24.63	0.6	—	—

Si substrate exhibits a very high surface quality (Fig. 2D, RMS roughness of only $0.5 \text{ nm}/25 \mu\text{m}^2$), the roughness of the surface increased to $2.2 \text{ nm}/25 \mu\text{m}^2$ (Fig. 2E) after transferring graphene, due to the monolayer of carbon atoms containing PMMA residues.⁷² After spin coating a TFSA/POFPMA layer onto the graphene, the roughness decreased to $0.4 \text{ nm}/25 \mu\text{m}^2$, corresponding with an optical quality of $\lambda/1000$ at a wavelength of 400 nm (Fig. 2F). Whereas the RMS roughness of the TFSA in nitromethane deposition was $14.9 \text{ nm}/25 \mu\text{m}^2$, the TFSA/POFPMA layer yielded an enhanced smoothness, even in comparison with the uncovered Si samples.

The homogeneity of the polymer layer was determined by X-ray photoelectron spectroscopy (XPS) measurements and is presented in Table 1. The atoms corresponding to TFSA only (sulfur and nitrogen) were not detected due to the low concentrations present in the obtained layer (ranging from 0.75–40 mM TFSA). The small standard deviation clearly confirmed the good uniformity of the polymer matrix layer.

The thickness of the spin coated layers as a function of the spin speed was determined by ellipsometry (see Fig. S3, ESI†). At a spin speed of 5000 rounds per minute (rpm), a thickness around $2 \mu\text{m}$ was obtained for the TFSA/POFPMA layer. The latter thickness was high enough to ensure a stable and robust layer for future doping tests (see Section 3.1.2).

Finally, the transparency of the TFSA/POFPMA layer was evaluated by optical transmission measurements (Fig. 2C). POFPMA is as PMMA a methacrylate-based polymer with additional fluorine atoms, POFPMA was expected to offer very high transparency. The transmission measurements confirmed that the spin coated layer hardly diminished ($A < 0.05\%$) the optical transmittance when coated onto a glass substrate. The oscillations and the slightly higher transmittance of the TFSA/POFPMA layer compared to the bare glass substrate are due to interference effects of the $2 \mu\text{m}$ thick polymer layer.

3.1.2 Doping of graphene with a spin coated TFSA/POFPMA layer. As TFSA was successfully incorporated in the POFPMA polymer layer featuring optical quality, as evidenced in Section 3.1.1, we determined in a next step the doping efficiency of TFSA/POFPMA by spin coating the dopant layer on monolayer graphene provided by CVD growth and electrochemically transferred onto flat Si substrates. Graphene is characterized by important parameters such as the charge carrier concentration (n in cm^{-2}), the mobility (μ in $\text{cm}^2 \text{V}^{-1} \text{s}^{-1}$) and the sheet resistance (R_s in Ωsq^{-1}).

These electrical parameters were monitored and quantified *via* Hall effect measurements prior and after doping. Transferred CVD graphene itself features a slight p-doping with n of the order of $(2-6) \times 10^{12} \text{ cm}^{-2}$. When applying additional p-doping, one expects to extract electrons from graphene, creating more holes in graphene, thus increasing the concentration of charge carriers while simultaneously decreasing the sheet resistance. Consequently, we expressed the doping efficiency in terms of the change in charge carrier concentration; $\Delta n = n_{\text{after doping}} - n_{\text{before doping}}$ (cm^{-2}) and the decrease in sheet resistance = $R_{s_{\text{after doping}}}/R_{s_{\text{before doping}}} \times 100$ (%). TFSA concentrations ranging from 0 to 40 mM were applied in combination with POFPMA onto graphene. The obtained results are shown in Fig. 3 and Table S1 (ESI†).

For every dopant concentration applied, an increase in graphene doping was obtained with a positive Δn between $+4.8 \times 10^{12}$ and $+3.8 \times 10^{13} \text{ cm}^{-2}$, corresponding to a decrease in Fermi level of 0.13 and 0.55 eV, respectively. For the latter values, a starting Fermi level of -0.23 eV was calculated for the undoped graphene, so after doping we obtained a Fermi level of respectively, -0.36 eV and -0.78 eV , depending on the doping concentration applied. The maximal increase in charge carrier concentration was accompanied with a strong decrease in sheet resistance, resulting in a value of 37.5% of its initial value after doping, which ranges between 900 and $2000 \Omega \text{sq}^{-1}$. Although fluorine atoms are present in the POFPMA polymer in contrast to PMMA, pure POFPMA has a negligible doping effect of only $\Delta n = +1.4 \times 10^{12} \text{ cm}^{-2}$. TFSA incorporation highly augments the doping with an optimal effect at a TFSA concentration of 15 mM. Further increase of the TFSA concentrations leads to saturation of the doping effect due to stronger intermolecular repulsive forces of charged TFSA molecules⁷³ and an increasing capturing probability for freely moving holes in the graphene sheet due to the presence of more ionized attraction centers in the dopant layer.⁷⁴ This doping regime with a saturation mechanism above a specific concentration is similar to that of F4-TCNQ/MEK doping⁴⁸ and was also observed earlier on for TFSA doping.⁴² In this way, we were able to dope graphene in a controllable manner without saturation when varying the TFSA concentration between 0 and 15 mM. Every concentration higher than 15 mM resulted in the maximum doping increase of almost $+4 \times 10^{13} \text{ cm}^{-2}$.

Although we obtained a doping efficiency up to $\Delta n = +3.8 \times 10^{13} \text{ cm}^{-2}$ and a 72.5% decrease in the sheet resistance, we noted that spin coating of pure TFSA in nitromethane on graphene resulted in a higher doping efficiency.⁴² The use of a POFPMA matrix, to guarantee the optical quality, diminishes the doping efficiency of TFSA, but, the net increase of $\Delta n = +3.8 \times 10^{13} \text{ cm}^{-2}$ is in a range which is suitable to significantly and positively affect the optical properties of graphene at the common telecom wavelength of 1550 nm (see Section 2.2.2). Not only the optical quality benefits from the use of the developed POFPMA matrix but also the stability is highly improved. Since TFSA reacts violently with water, the slightest environmental moisture causes a change in the observed doping effect. To overcome this instability, the spin coated POFPMA matrix serves as a protective layer; while the maximum increase in

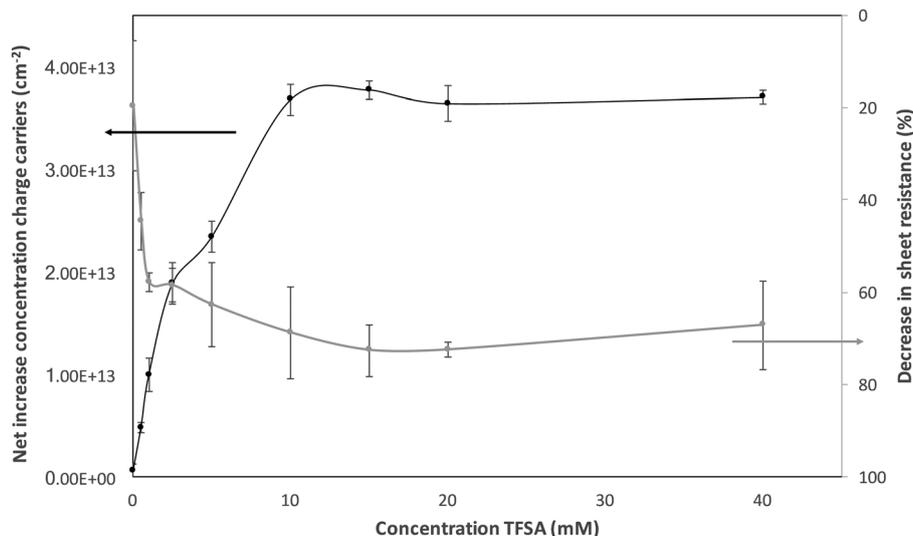


Fig. 3 Change in charge carrier concentration (Δn in cm^{-2} , black line and left y-axis) and decreasing sheet resistance (%), starting from CVD grown graphene on copper followed by transfer to Si substrates and subsequent doping with a TFSA/POFPMA layer, as a function of the TFSA concentration ranging from 0 to 40 mM. Each dopant solution is applied on three different samples.

charge carrier concentration was obtained after three days (the latter period was needed to set-in the maximum electron exchange from graphene to dopant layer and the waiting period to obtain the maximum doping efficiency was also notified with the use of the organic F4-TCNQ/MEK dopant layer⁴⁸), a change of only 10% was noticed for a period of several months (Fig. S4, ESI†). Compared to the previously reported TFSA doping experiments,^{35,38} the latter use of TFSA in POFPMA offered a significant increase in stability in function of time.

As an intermediate while important conclusion, TFSA embedded in the developed POFPMA polymer layer and applied through spin coating reveals to be a successful approach to apply TFSA as p-dopant for optical applications. The doping is controllable by using different concentrations TFSA mixed in POFPMA (20 w/v% in acetone) over a wide window, ranging from $\Delta n = +1.4 \times 10^{12} \text{ cm}^{-2}$ to $+3.8 \times 10^{13} \text{ cm}^{-2}$.

In the following section, we will extend the above described and acquired knowledge of the TFSA/POFPMA doping method for localized application on a graphene-covered optical waveguide.

2.2 TFSA/POFPMA doping on a graphene-covered silicon waveguide

2.2.1 Characterization of inkjet printed TFSA/POFPMA deposition.

TFSA/POFPMA dissolved in acetone served as an ideal dopant strategy to control graphene's Fermi level *via* spin coating when the dopant is deposited onto large graphene areas. However, when applying the dopant onto optical waveguides, it is an important advantage if the dopant deposition can be well localized at a precisely chosen position on the chip. Indeed, this allows doping different waveguides with different doping efficiencies *e.g.* by changing the dopant concentration used for various waveguides. Spin coating does not enable such a flexibility because it results in a total spreading of the dopant on the chip surface. Furthermore, whereas applying

spin coating is straightforward on planar substrates, this is not necessarily the case for spin coating on photonic chips containing non-planarized waveguides (*i.e.* waveguides that 'stick out' from the substrate surface as we considered here). Therefore, when applying graphene on a waveguide, we selected inkjet printing as technique to deposit TFSA/POFPMA, enabling micrometer-sized local depositions starting from a liquid ink. Unfortunately, we could not apply the dopant composition optimized for spin coating conditions (TFSA/POFPMA (20 w/v%) in acetone) for the inkjet printing, due to the high vapor pressure of acetone⁷⁵ (30 kPa at 20 °C). We therefore replaced acetone by the OFPMA monomer as solvent, which yielded a straightforward printable ink, exhibiting much structural similarity with the polymer material POFPMA itself. A concentration of 20 w/v% POFPMA in OFPMA was applied. Concentrations higher than the latter value could not be printed due to obstructions of the print nozzles.

When printing on a flat graphene sample, lined patterns were obtained as shown on the microscopy image in Fig. 4A. The width of the lines is 125 μm , regardless the number of printed layers. The obtained resolution confirmed inkjet printing as a promising tool to dope graphene with micro-scale precision on a photonic chip. Furthermore, when printing a three-layered TFSA/POFPMA line, we obtained a 3D-pattern. Its cross section, presented in Fig. 4B, clearly reveals the well-known 'coffee-ring' effect. This phenomenon occurs during drying of the droplets where an increased solvent evaporation rate towards the edges of the patterns lead to an accumulation of the material.⁷⁶ Nevertheless, the center of the printed line still possesses a height of 380 nm, which was sufficient to ensure good robustness and coverage level of the dopant deposition on the 220 nm high waveguide (see Section 2.2.2). Since the applied deposition technique is vastly different compared to spin coating, AFM measurements were executed to quantify the

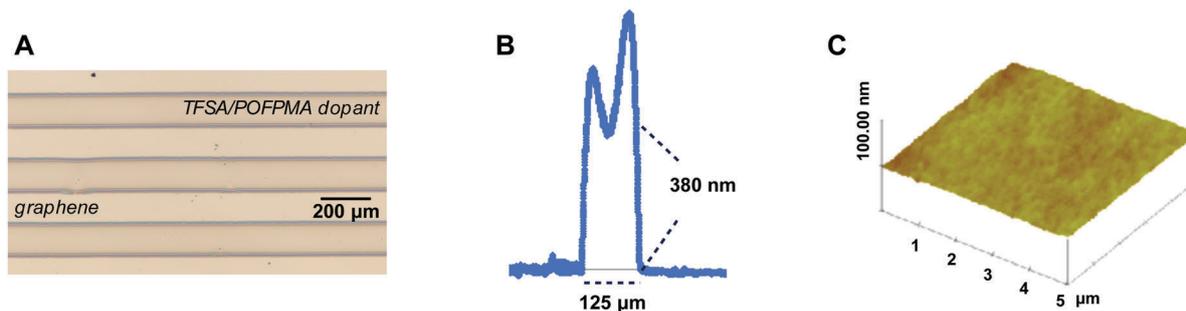


Fig. 4 TFSA/POFPMA lines (3 layers) printed on graphene transferred on flat silicon (A), a cross section of a printed line (measured with stylus profilometry) (B) and an AFM 3D surface plot in the center of the printed dopant deposition (C).

roughness of the printed patterns, resulting in a RMS roughness of $0.8 \text{ nm}/25 \mu\text{m}^2$ (shown in Fig. 4C). Despite the slight increase in the TFSA/POFPMA roughness for the printed TFSA/POFPMA deposition compared to the spin coated roughness ($0.4 \text{ nm}/25 \mu\text{m}^2$), it still fulfills the objectives for optical-quality requirements (RMS roughness $< 5 \text{ nm}/25 \mu\text{m}^2$), as stated in the introduction.

We also verified the doping capability of the inkjet-printed TFSA/POFPMA dopant deposition on flat graphene-covered Si substrates. The characterization procedure has been as follows: we initially carried out Hall measurements on the flat graphene-covered sample prior to doping. Subsequently, we inkjet-printed several TFSA/POFPMA dopant lines (see Fig. 4A), and repeated the Hall measurements afterwards. We observed that the inkjet-printed dopant lines yielded an increase in charge carrier concentration and a decrease in sheet resistance, as we expected and which is in agreement with the trend observed for the spin coated doping strategy and presented in Fig. 3. It should be noted that, whereas the spin coated TFSA/POFPMA dopant layer caused a full coverage of the graphene surface, the inkjet printed dopant deposition only partially covered the graphene surface (see Fig. 4A, showing a zoom-in of three printed lines). We verified that the change in charge carrier concentration for the sample with the printed lines was proportional to the change in charge carrier concentration for the sample with the spin coated layer multiplied by the surface coverage of the printed lines. The data can be found in the ESI,† (Fig. S5 and Table S2).

To complete the analysis of the printed TFSA/POFPMA dopant, we applied it to a photonic chip with Si waveguides to examine

the influence of the TFSA/POFPMA deposition on the waveguides (without graphene) by performing optical transmission measurements prior and after TFSA/POFPMA deposition. The results have shown negligible transmission change for a length of $700 \mu\text{m}$ dopant deposition, indicating that TFSA/POFPMA has a negligible effect on the optical absorbance or scattering of the light through the waveguide.

2.2.2 Doping efficiency of TFSA/POFPMA on graphene-covered Si waveguides. After the confirmation of the doping capacity of the inkjet-printed dopant through Hall measurements, we continued by applying the TFSA/POFPMA dopant onto an SOI chip with straight Si waveguides covered with graphene over small distances, namely $100 \mu\text{m}$, $200 \mu\text{m}$ and $300 \mu\text{m}$ graphene strip lengths on different sections of the chip. Since Hall measurements are challenging on graphene with dimensions of the order of $100 \mu\text{m}$, we examined the doping efficiency with optical transmission measurements.

To assess the absorption induced by undoped graphene, the optical transmission of different graphene-covered Si waveguides was measured, without dopant. The transmission was characterized at the telecom wavelength of 1550 nm . In a second measurement, the optical transmission of the same waveguides was characterized, this time additionally covered with TFSA/POFPMA dopant applied by inkjet printing. Due to a relatively slower drying process of the printed deposition in comparison with the spin coated deposition, we applied a TFSA concentration of 40 mM . The latter concentration is situated in the saturated regime of the doping efficiency (see Fig. 3), to

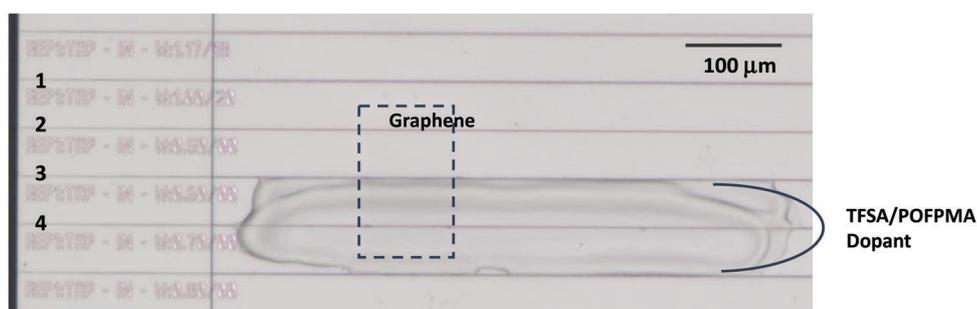


Fig. 5 An optical microscopy image of a section of the optical chip. Graphene with a strip length of $100 \mu\text{m}$ was on top of the waveguides (indicated with the dotted line rectangular shape) and TFSA/POFPMA dopant was deposited *via* inkjet printing. Four waveguides are also indicated with number 1–4.

ensure effective doping. An example of the chip lay-out, for the region with a 100 μm graphene strip length after doping is presented in Fig. 5. Four waveguides, indicated with number 1–4, can be observed, which were all measured in the first and second transmission measurements. Additionally, the graphene region covers three waveguides (2–4) while the dopant only covers waveguides 4 as can be seen in Fig. 5. Whereas the waveguide with number 1 was the reference waveguide (without graphene

and dopant), the waveguide 4 was our target waveguide where graphene and later doping was applied. This waveguide has a width of 0.7 μm . Meanwhile, we executed reference measurements on waveguide 1 during the first and second optical transmission measurements and observed a similar optical insertion loss, as expected. Therefore, we could compare the obtained results of both measuring cycles. Similar experimental chip lay-outs and measurements were performed for the other

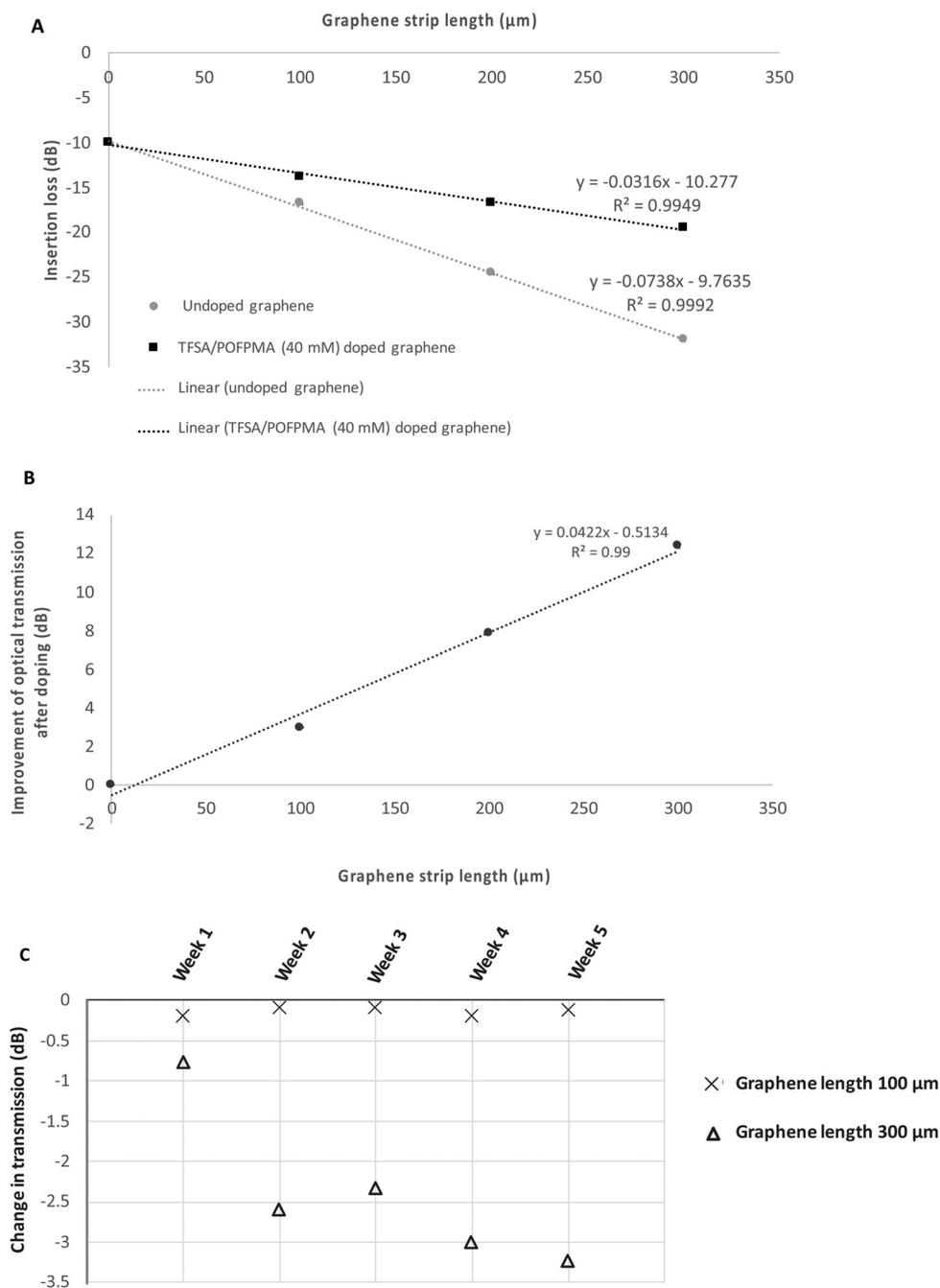


Fig. 6 (A) The optical transmission at a wavelength of 1550 nm, measured for graphene-covered waveguides (with a width of 0.7 μm) without and with TFSA/POFPMA (40 mM) dopant (grey and black, respectively) and (B) the improvement in transmission for doped graphene-covered Si waveguides in function of graphene strip length. (C) Stability measurement by monitoring the change in optical transmission in function of time (averaged per week, with graphene lengths of 100 and 300 μm). The error on the optical transmission measurements was less than 5%.

sections on the same chip where similar waveguides with the same dimensions have been fabricated but that were covered with 200 μm and 300 μm graphene strip length, respectively.

In Fig. 6 the optical transmissions are shown for the waveguides 4 with a width of 0.7 μm and with varying graphene lengths on top, measured when the graphene is undoped and when the graphene is doped with TFSA/POFPMA. We observed that the loss induced by the undoped graphene was equal to 7.38 dB per 100 μm graphene length (for the TE-polarized waveguide mode). This value is extracted from the slope of the grey line in Fig. 6A. It is clear from these measurements that the insertion loss has a linear relation to the graphene length, as expected.¹² For the doped graphene-covered Si waveguides, the induced loss was decreased: it became 3.16 dB per 100 μm graphene length (extracted from the slope of the black line in Fig. 6A). Hence the doping-induced improvement in optical transmission for the waveguides was 4.22 dB per 100 μm graphene length, as shown in Fig. 6B. The latter clearly revealed the linear correlation of the enhanced transmission with the graphene length.

To the best of our knowledge, these are the first reported experiments based on an inkjet printed dopant on graphene-covered waveguides, with promising results in view of the strong average transmission increase around 4.22 dB per 100 μm graphene length as compared to undoped graphene-covered waveguides.

The stability of the printed deposition was monitored over a period of several weeks. The change of the optical transmission of the doped graphene-covered waveguides is presented in Fig. 6C. The originally obtained transmission values were guaranteed for that period of time for a graphene length of 100 μm . For a graphene strip length of 300 μm however, the doping-induced transmission increase started to diminish after some weeks (around 3 dB transmission decrease after 5 weeks, which is still a modest decrease compared to the starting value in Fig. 6A). The doping stability of the inkjet printed TFSA/POFPMA dopant was less compared to that of the spin coated deposition. The main reason for this significant difference is the thickness of the deposition which is 5 times less for the inkjet-printed deposition compared to the spin coated layers. In addition, the surface-volume ratio is also higher for the printed deposition, which enlarges the exposure to a humid environment for the TFSA molecules.

Finally, we calculated the theoretical doping level from the obtained optical transmission data *via* MODE simulations (see Experimental methods in ESI†). According to the simulations, the final Fermi level after doping graphene should be around -0.45 eV for an increase in linear optical transmission of 4.22 dB per 100 μm graphene on a Si-waveguide (see experimental results above). This corresponds to an increase (in absolute value) of the Fermi level of 0.22 eV, when -0.23 eV was determined as initial Fermi level. The 0.22 eV increase is lower than the change in Fermi levels obtained for graphene doped with spin coated TFSA/POFPMA layers (a maximum change of the Fermi level of 0.53 eV for a TFSA concentration of 40 mM was described in Section 3.1.2). Probably, both the volume of the doping layer and the deposition method with another solvent (acetone compared to liquid OFPMA) are the

reasons underlying these findings. However, the increase in optical transmission of 4.22 dB per 100 μm of graphene length is remarkable and promising for future optical applications.

3. Conclusion

The present work described an optical doping strategy for graphene, based on a TFSA/POFPMA layer. The developed dopant consists of TFSA as super acid and thus a strong p-type dopant, and POFPMA as polymer matrix. The latter was applied to improve, on the one hand the optical quality, and on the other hand the environmental stability over time. The former optical quality was confirmed by a low surface roughness of only 0.4 nm/25 μm^2 and a very high transparency ($A < 0.05\%$) over the wavelength range between 500 and 1900 nm.

TFSA/POFPMA can be applied in a straightforward fashion onto large area graphene *via* spin coating. We quantified the doping efficiency by monitoring graphene's electrical parameters through Hall measurements: an increase of charge carrier concentration (holes) between $+4.8 \times 10^{12}$ cm^{-2} and $+3.8 \times 10^{13}$ cm^{-2} was observed, for varying TFSA concentrations between 0 and 40 mM.

Furthermore, the TFSA/POFPMA dopant could also be deposited in localized micrometer-sized patterns using inkjet printing. A three-layer thick print line featured sufficient height to cover a 220 nm high waveguide and the printed line also offered a low surface roughness of only 0.8 nm/25 μm^2 , without inducing any additional propagation losses. The optical transmission was strongly improved when doping a graphene-covered waveguide: a transmission increase of 4.22 dB/100 μm graphene length at a wavelength of 1550 nm was obtained. Both deposition methods showed significant stability of the doping efficiency as a function of time for a period of at least five weeks.

The herein reported tests were the first in their kind using inkjet-printed dopants and allow enhanced optical transmission of graphene-covered waveguides. The developed methodology will be very promising when exploiting graphene for future optical and photonic applications.

Conflicts of interest

There are no conflicts to declare.

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